

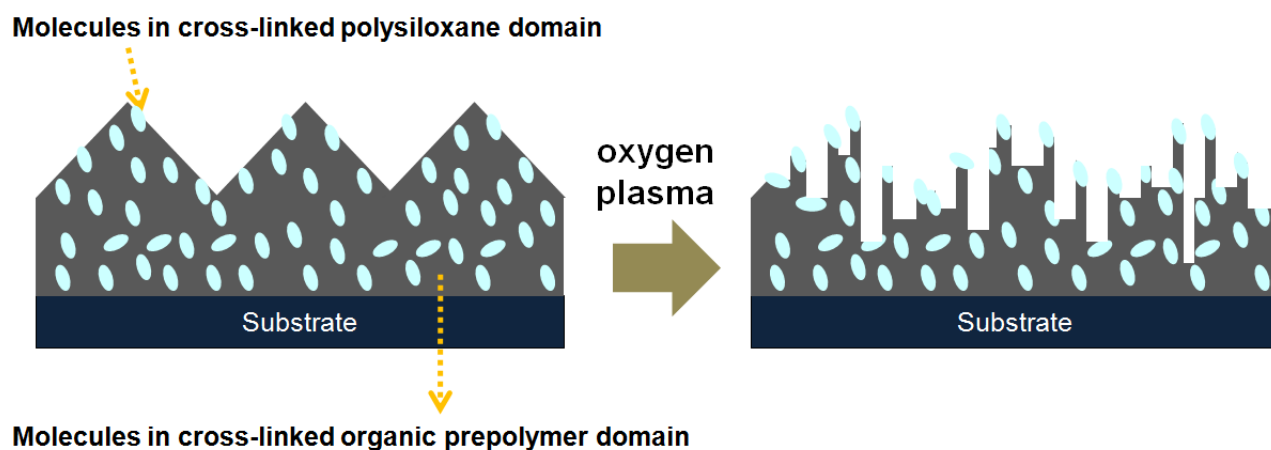
Supplementary Material (ESI) for Journal of Materials Chemistry

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## Supporting Information

### Fabrication of Hierarchical Structure by Oxygen Plasma Etching of Photo-Cured Microstructure Containing Silicon Moiety

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**Figure S1.** Schematic illustration for explaining the mechanism of the selective etching process to realize hierarchical structures.